

AMENDMENTS TO THE SPECIFICATION

Please replace the first full paragraph on page 13 with the following amended paragraph:

As shown in Figures 4, 5A and 5B, at each of the exposure areas ~~166_{mm}~~168_{mm} to ~~166_{mm}~~168_{mm}, a digital micromirror device (DMD) 50 is provided to serve as a spatial light modulation element for modulating an incident light beam at each of pixels in accordance with image data. The DMD 50 is connected with an unillustrated controller, which is provided with a data processing section and a mirror driving control section.

Please delete the present Abstract of the Disclosure.

Please add the following new Abstract of the Disclosure:

An imaging head faces an imaging surface and is relatively moved along the scanning surface in a predetermined scanning direction. The imaging head includes an imaging element group and an alteration section. The imaging element group is structured by a plurality of imaging elements, which are arranged two-dimensionally in a plane substantially parallel to the imaging surface. The imaging element group generates a group of image pixels at the imaging surface in a two-dimensional arrangement which is inclined, as a whole, at a predetermined inclination angle with respect to the scanning direction. The alteration section alters a number of image pixels in a direction which is inclined from the scanning direction by the inclination angle, on the basis of a difference between the predetermined inclination angle of the imaging element group and an actual inclination angle of the image pixel group. ~~In other words, if an actual inclination angle of an exposure area is offset from an ideal inclination angle, images are recorded with the number of pixels employed in a row direction having been altered in accordance with the actual inclination angle. Accordingly, variation of a pitch P can be suppressed to a certain range.~~